

2/6

Fig. 2

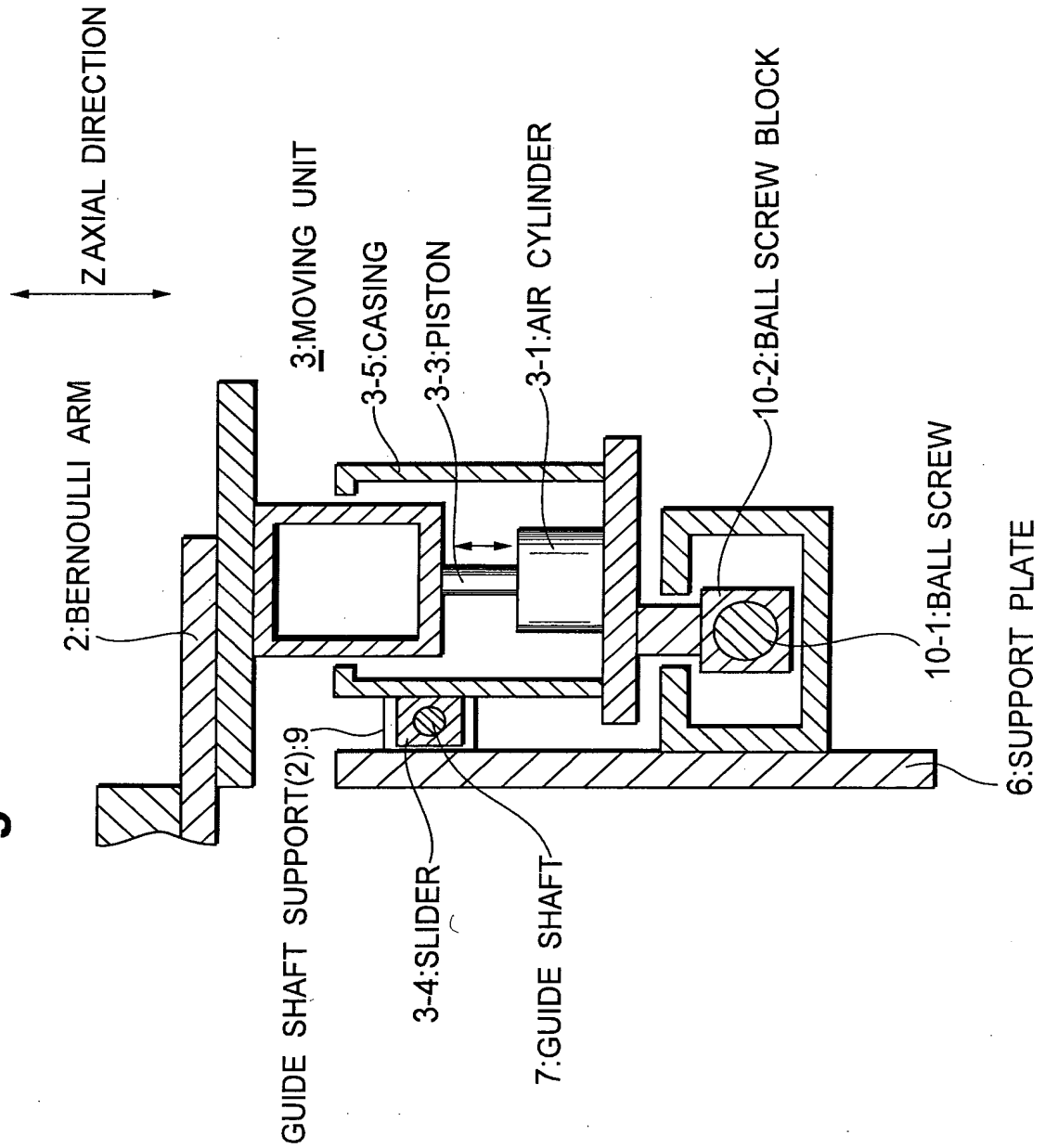


Fig. 1 is a schematic diagram of a measurement apparatus. It shows a vertical assembly with a horizontal bar (10) and a vertical rod (11). A vertical arrow indicates the 'ZAXIAL DIRECTION'. Two horizontal lines are labeled 'H0' and 'H1'. A dimension line on the right is labeled 'P1 P0'.

Fig. 4(b)

Fig. 4(b)

Diagram illustrating a semiconductor processing apparatus, showing various components and their arrangement:

- 11: GAS INTRODUCING PORTION**
- 22: MOVING UNIT DRIVER**
- 26: SUPPORT PLATE**
- Z AXIAL DIRECTION**
- 27-1: GUIDE SHAFT(1)**
- 28-1: GUIDE SHAFT SUPPORT(1)**
- 3: MOVING UNIT**
- 22: MOVING UNIT DRIVER**
- 28-3: GUIDE SHAFT SUPPORT(3)**
- 27-2: GUIDE SHAFT(2)**
- 14: WAFER**
- 21-1: PIN**
- 30-1**
- 21: WORK PUSHING-UP PORTION**

5/6

Fig. 5

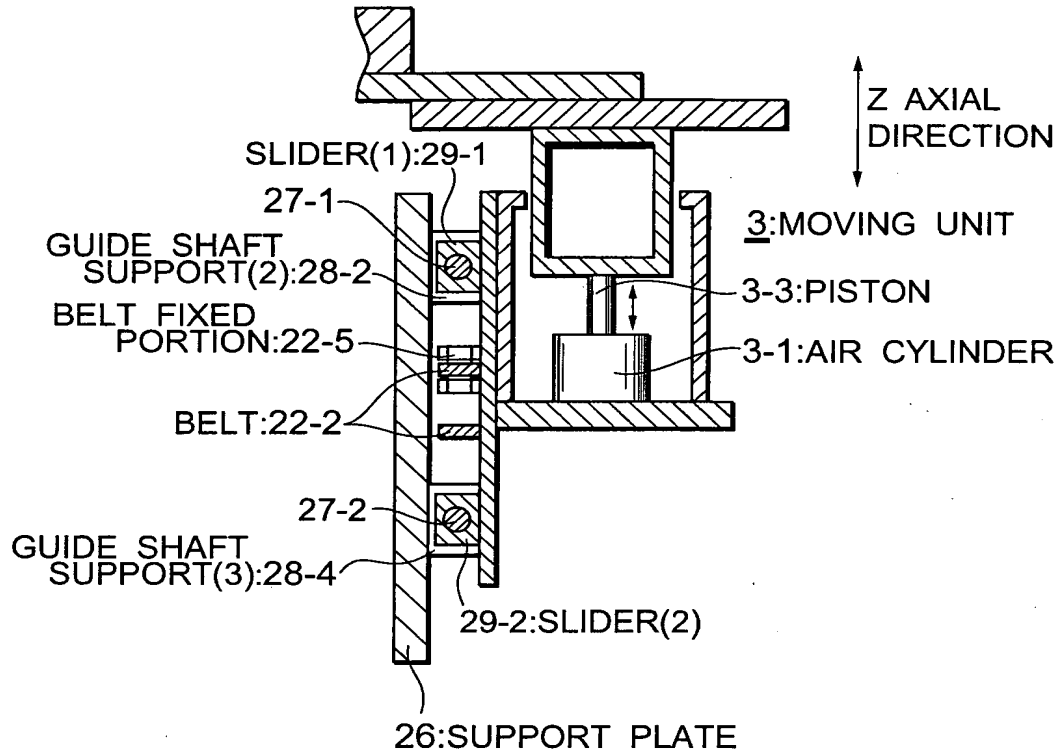
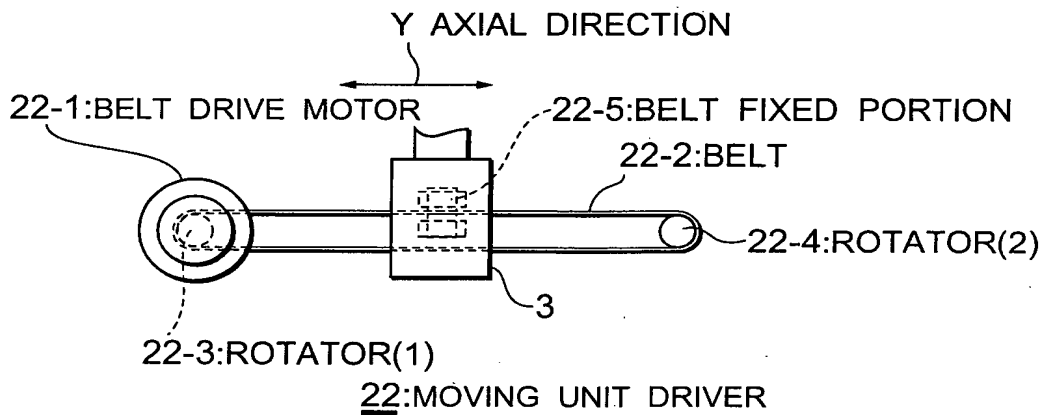


Fig. 6



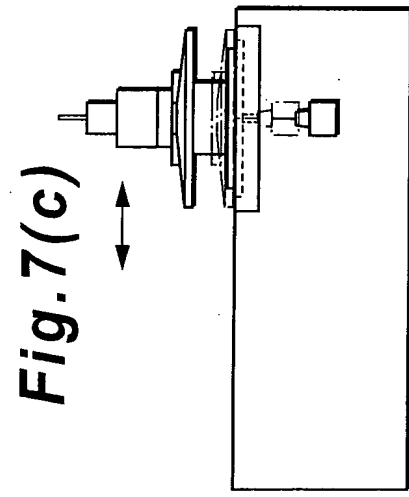
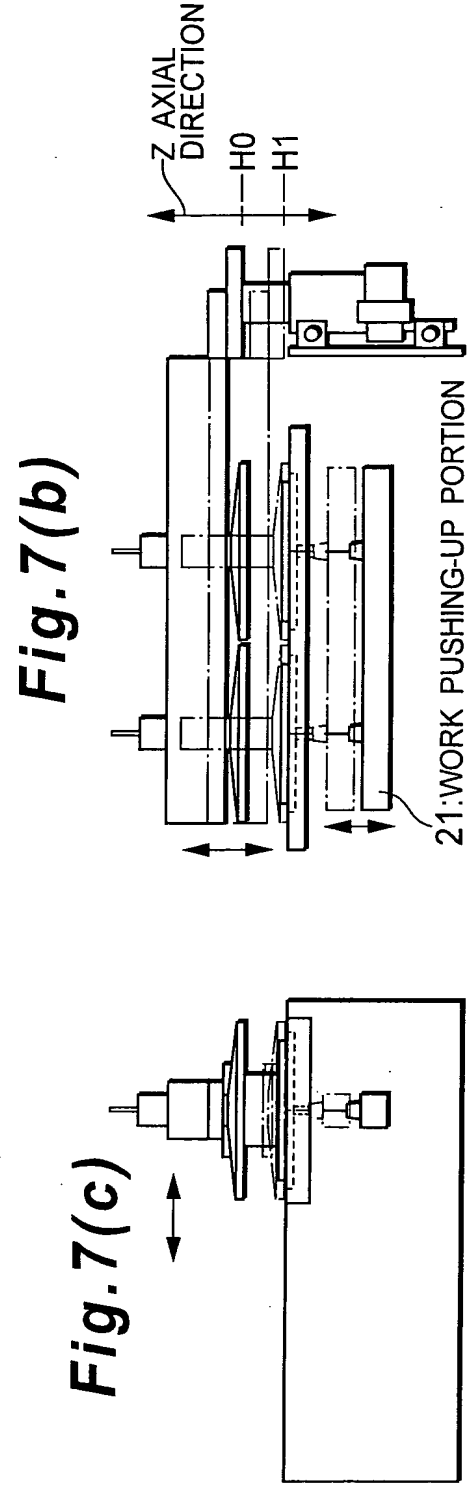
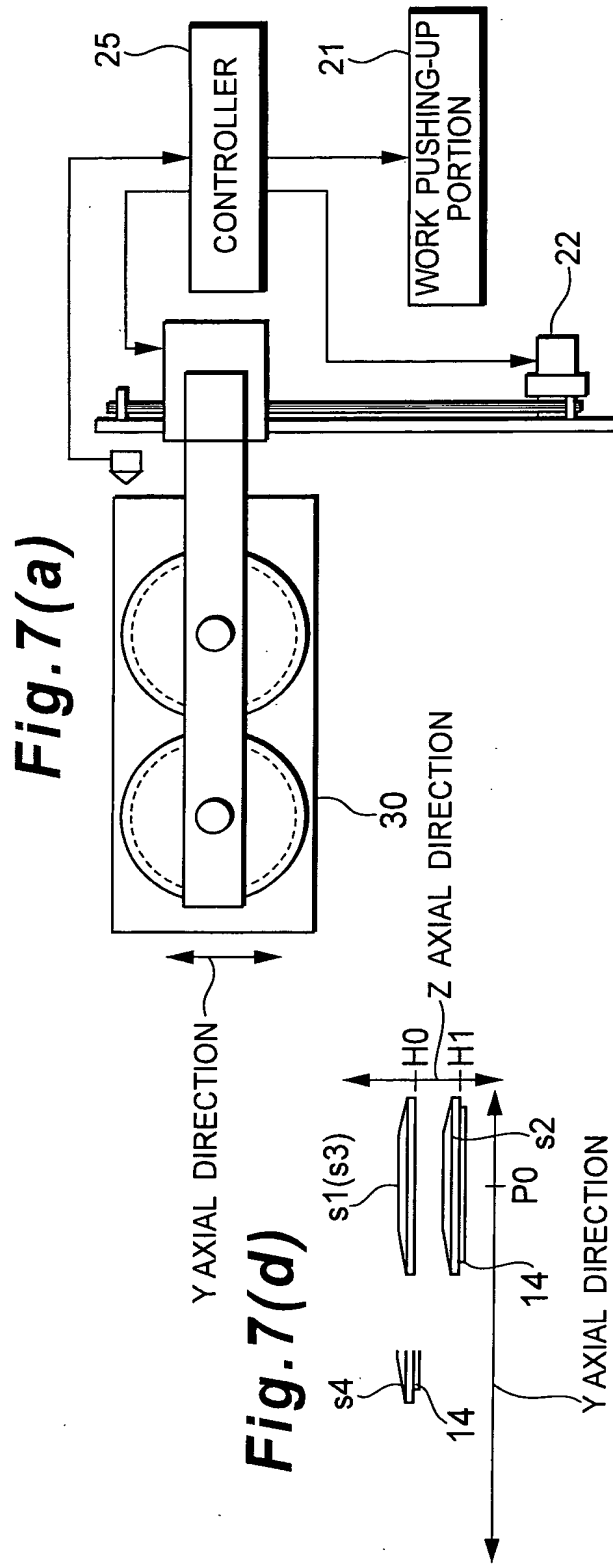


Fig. 7(d)